



MAGEVA

Sputtering & Evaporation **Universal** System

The MAGEVA thin film deposition system is a flexible tool, which operates, **ALL IN ONE**, either in **thermal evaporation** or **sputter deposition**.

Compact, for better utilization of clean room and laboratory space, the frame is equipped with wheels for quick and effortless transportation.

The stainless steel chamber, fitted with turbo and rotary pumps, allows user to change process in less than 10 minutes. MAGEVA pumps down very quickly to high vacuum (10^{-6} mbar range).



The system is available in three versions, depending on the size of the magnetron sputtering cathode:

- MAGEVA-50
- MAGEVA-75
- MAGEVA-100

MAGEVA is suitable for both research and small lot production requirements.

Safe and CE
Automated interlocks ensure safe operation at all times; an emergency stop button protect both operator and machine. All power distribution and system controls are enclosed in the cabinet. MAGEVA carries the CE conformity marking.

MAIN FEATURES	Standard	Option
SS chamber ISO 250 x 250 mm height	X	
Quick-access door and viewport	X	
Sample holder 100 mm x 100 mm	X	
Gaz entry with fine adjustment valve for sputtering	X	
Mass flow controller		X
Turbo pump 240 l/s	X	
Primary rotary vane pump 17 m ³ /h	X	
Primary dry pump		X
Manual gate valve ISO 100	X	
2" cathode magnetron	mageva-50	
3" cathode magnetron	mageva-75	
4" cathode magnetron	mageva-100	
Thermal evaporator (filament and evaporation boat holder)	X	
Full range gauge (10 ⁻⁹ to 1200 mbar)	X	
6 MHz quartz sensor probe with Q-Pod	X	
DC power supply 1.5 kW for sputtering	X	
DC power supply 10 V 330 A for thermal effect	X	
Total dimensions (with frame) 110 cm L x 70 cm l x 140 cm H	X	
Weight 90 kg	X	

